

ABSTRACT

END EFFECTOR OF WAFER TRANSFER ROBOT WITH EMBEDDED SENSORS

An end effector, which is connected to a wafer transfer robot, includes a main member, a sensor and a lid. The main member has a first room on a side thereof, in which the sensor is received. The lid is fixed to the main member to cover the sensor. The sensor transmits a vibration signal to a central controller when the main member is vibrating. The end effect may work in a narrow space to transfer wafers and still keep high sensible and precise detection of vibration.

Figure 1